

LIST OF ALLOWED CLAIMS

(Original)

WHAT IS CLAIMED IS:

1. A positioning device comprising an object table, a sub-system for processing an object to be placed on the object table, a drive unit for displacing the object table relative to the sub-system, and a measuring system for measuring a position of the object table relative to the sub-system, the drive unit comprising a stationary part which is fastened to a first frame of the positioning device, while the measuring system comprises a stationary part and a movable part which is fastened to the object table for cooperation with the stationary part of the measuring system, characterized in that the stationary part of the measuring system is fastened to a second frame of the positioning device which is dynamically isolated from the first frame.

2. (Amended) A positioning device comprising an object table, a sub-system for processing an object to be placed on the object table, a drive unit for displacing the object table relative to the sub-system, and a measuring system for measuring a position of the object table relative to the sub-system, the drive unit comprising a stationary part which is fastened to a first frame of the positioning device, while the measuring system comprises a stationary part and a movable part which is fastened to the object table for cooperation with the stationary part of the measuring system, characterized in that the stationary part of the measuring system is fastened to a second frame of the positioning device which is dynamically isolated from the first frame, and in that the sub-system is fastened to the second frame.

3. A positioning device as claimed in claim 1, characterized in that the
 15 object table is displaceable over a guide parallel to at least an X-direction, the guide
 being fastened to the second frame.

4. A lithographic device comprising a radiation source, a mask table, a
 projection system having a main axis, a substrate table, a drive unit for displacing the
 20 substrate table relative to the projection system in at least one direction perpendicular
 to the main axis, and a measuring system for measuring a position of the substrate
 table relative to the projection system, the drive unit comprising a stationary part
 which is fastened to a first frame of the lithographic device, while the measuring
 system comprises a stationary part and a movable part which is fastened to the
 substrate table for cooperation with the stationary part of the measuring system,
 25 characterized in that the stationary part of the measuring system is fastened to a
 second frame of the lithographic device which is dynamically isolated from the first
 frame.

5. A lithographic device as claimed in claim 4, characterized in that the
 substrate table is displaceable over a guide which extends perpendicular to the main
 30 axis and is fastened to the second frame.

6. (Amended) A lithographic device comprising a radiation source, a mask table, a projection system having a main axis, a substrate table, a drive unit for displacing the substrate table relative to the projection system in at least one direction perpendicular to the main axis, and a measuring system for measuring a position of the substrate table relative to the projection system, the drive unit comprising a stationary part which is fastened to a first frame of the lithographic device, while the measuring system comprises a stationary part and a movable part which is fastened to the substrate table for cooperation with the stationary part of the measuring system, characterized in that the stationary part of the measuring system is fastened to a second frame of the lithographic device which is dynamically isolated from the first frame, and in that the lithographic device comprises a further drive unit for displacing the mask table relative to the projection system in a scanning direction perpendicular to the main axis, the further drive unit comprising a stationary part which is fastened to the first frame, while the substrate table is displaceable relative to the projection system parallel to at least the scanning direction, the measuring system comprising a further stationary part which is fastened to the second frame and a further movable part which is fastened to the mask table for cooperation with the further stationary part of the measuring system for measuring a position of the mask table relative to the projection system or for measuring a position of the mask table relative to the substrate table.

7. A lithographic device as claimed in claim 6, characterized in that the
10 mask table is displaceable over a first guide extending parallel to the scanning
direction and the substrate table is displaceable over a second guide extending
perpendicularly to the main axis, the first guide and the second guide being fastened
to the second frame.

8. (Amended) A lithographic device comprising a radiation source, a mask table,
a projection system having a main axis, a substrate table, a drive unit for displacing the
substrate table relative to the projection system in at least one direction perpendicular to the
main axis, and a measuring system for measuring a position of the substrate table relative to
the projection system, the drive unit comprising a stationary part which is fastened to a first
frame of the lithographic device, while the measuring system comprises a stationary part and
a movable part which is fastened to the substrate table for cooperation with the stationary part
of the measuring system, characterized in that the stationary part of the measuring system is
fastened to a second frame of the lithographic device which is dynamically isolated from the
first frame, and in that the projection system is fastened to the second frame.